	1	10.	The method of claim 1, wherein at least 1% of the electroactive ceramic is
	2		removed during laser machining.
	3		
	4	11.	The method of claim 10, wherein at least 5% of the electroactive ceramic is
	5		removed during laser machining.
	6		
	7	12.	The method of claim 10, wherein at least 20% of the electroactive ceramic is
	8		removed during laser machining.
	9		
	10	13.	The method of claim 10, wherein at least 50% of the electroactive ceramic is
	11		removed during laser machining
	12		
	13	14.	The method of claim 10, wherein at least 75% of the electroactive ceramic is
	14		removed during laser machining.
	15		
	16	15.	The method of claim 10, wherein at least 90% of the electroactive ceramic is
	17		removed during laser machining.
	18		
	19	16.	The method of claim 1, wherein the electroactive ceramic possesses a surface area
	20		at least 10% greater after machining than its surface area before machining.
	21		•
	22	17.	An electromechanical device, comprising
	23		a substantially planar electroactive ceramic member having grooves defined on a
	24		planar surface of the member, whereby the grooves allow the member to
	25		conform to a curved surface.
	26		
	27	18.	The electromechanical device of claim 17, wherein the device is an
	28		electromechanical sensor or actuator.
	29		